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Status of 3D detector development at SINTEF for ITk upgrade

SINTEF in collaboration with University of Oslo have been performing R&D activities on 3D detectors with the aim to qualify to be a production site for ITk upgrade. In this context, a 3D detector fabrication run has been completed recently with very promising results. Various sensor geometries with active edges were implemented, and the fabrication was carried out on 6-inch Si-Si wafers with sensor substrate thicknesses of 100 μm and 50 μm using single-sided processing approach. We will present the electrical test results; assembly, irradiation and test beam plans; and the plans for the next fabrication run.

Primary author: KOYBASI, Ozhan (SINTEF)

Co-authors: Dr POVOLI, Marco (SINTEF MiNaLab); KOK, Angela (SINTEF); Dr SUMMANWAR, Anand (SINTEF); Dr BREIVIK, Lars (SINTEF); Mr HANSEN, Trond (SINTEF); Mr LIETAER, Nicolas (SINTEF); ROHNE, Ole (University of Oslo (NO)); SANDAKER, Heidi (University of Oslo (NO))

Presenter: Dr POVOLI, Marco (SINTEF MiNaLab)